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MEMS for Ultrasound

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Message from the Guest Editors

Micro-electro-mechanical systems (MEMS) technology has demonstrated enormous potential in constructing micro transducers and micro sensors with outstanding performance due to its advantages of, for instance, miniaturization, high speed, high resolution, high temperature reliability, and convenience of batch fabrication. MEMS Ultrasound devices have been found to be useful in a diverse range of applications such as medical, microscopy, inkjet printing, non-destructive structure testing, fluid/particle manipulation, wireless power transfer, and other harsh conditions where conventional ultrasound transducers tend to fail. The materials, designs, modeling, structures, fabrication, integration, reliability, and applications of MEMS for ultrasound involve multiple disciplines, demanding researchers with diverse backgrounds to investigate.

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